

The Development and the commercialization of the Mask Aligner for wafer
Midas System will continue to grow along with the value creation for our customers.

<http://www.aligner.co.kr>

MIDAS Mask Aligner MDA-600S



The MIDAS MDA-600S Mask aligner is good for research and variable process of all applications. It represents next generation of full-field lithography systems.



ITEM	SPECIFICATIONS
Substrate Size	Up to 6" diameter
UV Lamp Power	350W Lamp(350-450nm) or UV LED(365nm)
Uniform Beam Size	6.25"×6.25" or 160mm diameter, ±2% of Uniformity
365nm Beam Intensity	20-30mW/cm ² or ≤ 22mW/cm ²
Options	BSA, UV-LED, Namo-imprint



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